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# A fast and adaptive bi-dimensional empirical mode decomposition approach for filtering of workpiece surfaces using high definition metrology

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## a r t i c l e i n f o

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## A B S T R A C T

The surface topography of workpieces has an important influence on the final performances of the product. The digital filtering is a critical step to analyze the surface topography of workpieces. Bi-dimensional empirical mode decomposition (BEMD) approach is superior to conventional filtering approaches in the analysis of non-stationary and non-linear data. High definition metrology (HDM) can generate massive point cloud data to represent the three-dimensional (3D) surface topography of workpieces, which provides a new opportunity for surface topography analysis. This paper develops a fast and adaptive bi-dimensional empirical mode decomposition (FABEMD) approach for filtering of workpiece surfaces using HDM. Firstly, the neighboring window algorithm is presented to extract local extrema and draw the extrema spectrum. Secondly, the adaptive window algorithm is developed to automatically select the optimal window size of the order statistics filter, and plot the envelope spectrum. Finally, the average smoothing filter is presented for smooth filtering and generating of the mean envelope. The performance of the proposed FABEMD-based filter is validated by a simulated surface data and three real-world surface data. Compared with Gaussian filter (ISO 11562:1996, ASME B46.1-2002), the BEMD-based filter and the recent shearlet-based filter in the qualitative and quantitative analysis, the proposed FABEMD-based filter is superior for the separation and extraction of different surface components.

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## **1. Introduction**

The surface texture is an important index to evaluate the quality of workpieces  $[1,2]$ , and is generally described from the small to the large scale: roughness, waviness and form. It is well-known that different components of the surface texture have different influences on the functional performance of workpieces. To be specific, roughness is a good indicator of the surface irregularities, thus can be applied to detect errors in the material removal process, and also it has great influence on the workpiece functionality such as wear and friction. Waviness, which may occur from machine or work deflections, chatter, residual stress, vibrations, or heat treatment, has influence on tightness of workpieces. Form may directly affect the assembling performance of workpieces. Therefore, the motivation for separating these components derives from the fact that they

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have different origins and influences on workpieces functionalities in different ways. It is very important to separate the surface texture into different components before surface topography analysis.

Digital filtering is an essential step to realize the separation process. Filtering of workpiece surfaces has been a hot research topic on account of its importance for surface texture analysis. The traditional filtering approaches such as 2RC filter and Gaussian filter have been firstly studied, and the Gaussian filter is one of the most widely-used standard filtering approaches. However, it is well recognized that it is not robust against outliers. To overcome the shortcoming, some modified approaches such as robust regression Gaussian filter [\[3\],](#page-15-0) spline filter [[4\],](#page-15-0) robust spline filter [[5\],](#page-15-0) and morphological filter [\[6\]](#page-15-0) have been developed. Recent advances in filtering approaches are reviewed in [[7,8\].](#page-15-0)

Several researchers develop wavelet-based filtering approaches and apply them to analyze workpiece surfaces. Different from the previous filtering approaches, wavelet-based filters can provide multi-scale analysis since they can divide a surface profile into different frequency components and investigate each component with a resolution matched to its scale. Fu et al. [[9\]](#page-15-0)

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<span id="page-1-0"></span>adopted the wavelet transform to surface topography analysis and compared different wavelet bases. Orthogonal wavelet bases and biorthogonal wavelet bases were recommended due to their transmission characteristics of the corresponding filters. Jiang et al. [[10\]](#page-15-0) proposed a lifting wavelet representation for characterization of surface topography. Josso et al. [\[11\]](#page-15-0) proposed a frequency normalized wavelet transform for surface roughness analysis and characterization. Wang et al. [\[12\]](#page-15-0) proposed a modified anisotropic diffusion filter to separate workpiece surfaces into various scale-limited surfaces. Most recently, Du, Liu and Huang [[13\]](#page-15-0) presented a shearlet-based filtering approach. The workpiece surface was decomposed into different sub-bands of coefficients with non-subsampled shearlet transform (NSST). Then the surface components at different level were reconstructed based on inverse NSST.

Recently, Huang et al. [[14\]](#page-15-0) and Du et al. [\[15\]](#page-15-0) introduced and improved the empirical mode decomposition (EMD) approach to analyze one-dimensional non-stationary and non-linear signals based on instantaneous frequency. Flandrin [[16\]](#page-15-0) proposed the concept of filter banks based on EMD and the corresponding order intrinsic mode functions (IMFs) were combined to achieve the highpass, low-pass and band-pass filters. Wu and Huang [\[17\]](#page-15-0) confirmed that the EMD approach had similar filtering characteristics with the wavelet-based approaches. Boudraa and Cexus [\[18\]](#page-15-0) used different thresholds for each IMF to reconstruct the new filter and realize the signal denoising. Nevertheless, EMD cannot be used to analyze 3D data.

Nunes [\[19\]](#page-15-0) proposed a bi-dimensional EMD (BEMD) appraoch, which is a two-dimensional (2D) extension of the EMD approach, mainly used for image processing [[20\],](#page-15-0) image denoising [\[21\],](#page-15-0) image edge pattern processing [\[22\]](#page-15-0) and medical image registration [[23\],](#page-15-0) not used for filtering of workpiece surfaces. Moreover, since the window size of order statistic filters in the BEMD approach is not determined adaptively, it frequently does not have the best filtering results. Bhuiyan [[24,25\]](#page-15-0) proposed a fast and adaptive BEMD (FABEMD) approach. Simulation results demonstrate that FABEMD is not only faster and adaptive, but also outperforms the original BEMD in terms of the quality of the BIMFs.

With the development of on-line high definition measurement (HDM) technologies, great opportunities are provided for on-line controlling surface quality.Arepresentative of on-line HDMfor surface variation measurement is Shapix based on laser holographic interferometry metrology [\[26\],](#page-15-0) which measures 3D surface height map and gains millions of data points within seconds, and has 150  $\mu$ m resolution in x–y direction and 1  $\mu$ m accuracy in z direction. Based on HDM, some researches about surface quality control and engineering applications have been successfully conducted, such as surface classification [\[27,28\],](#page-16-0) tool wear monitoring [[29\],](#page-16-0) form error evaluation and estimation  $[30,31]$ , volume variation control [\[32\],](#page-16-0) and flat surface variation control [\[33\].](#page-16-0) However, to the best knowledge of the authors, there is no BEMD-based filtering approach for workpiece surfaces using HDM. The high density point cloud data of HDM is large. About one million measurement points are collected from a cylinder head by HDM system. So, HDM needs a fast and adaptive analysis. Therefore, this paper presents a novel fast and adaptive bi-dimensional empirical mode decomposition (FABEMD) approach for filtering of workpiece surfaces using HDM.

The remainder of this paper is organized as follows: The BEMD approach is briefly introduced in Section 2. In Section [3,](#page-2-0) the proposed approach of filtering workpiece surfaces is presented. In Section [4,](#page-4-0) a simulation experiment is conducted to validate the feasibility of the presented approach. In Section [5,](#page-6-0) three case studies using different kinds of workpiece surfaces are presented to show the effectiveness of the proposed approach. In Section [6,](#page-15-0) the conclusions of this study are drawn.

## **2. Brief introduction to BEMD**

The BEMD approach decomposes a signal into its bi-dimensional IMFs (BIMFs) and a residue based on the local spatial scales. Let the original signal be denoted as  $I(x, y)$ , a BIMF as  $F(x, y)$ , and the residue as  $R(x, y)$ . The original bi-dimensional signal  $I(x, y)$  can be decomposed by BEMD

$$
I(x, y) = \sum F_i(x, y) + R(x, y) \tag{1}
$$

where  $F_i(x, y)$  is the i-th BIMF obtained from its source signal  $S_i(x, y)$ y), and  $S_i(x, y) = S_{i-1}(x, y) - R_{i-1}(x, y)$ .

It requires one iteration or more to obtain  $F_i(x, y)$ , and the intermediate state of a BIMF in j-th iteration can be denoted as  $F_{Tj}(x, y)$ . The decomposition steps of the BEMD approach are summarized as follow:

Step 1: Set  $i = 1$  and  $S_i(x, y) = I(x, y)$ .

Step 2: Set  $j = 1$  and  $ST<sub>i</sub>(x, y) = S<sub>i</sub>(x, y)$ .  $ST<sub>j</sub>$  represents the input signal of the jth decomposition.

Step 3: Obtain the local maxima map of  $F_{Tj}(x, y)$ , denoted as  $P_j(x, y)$ y).

Step 4: Interpolate the maxima points in  $P_i(x, y)$  and generate the upper envelope, denoted as  $U_{Ei}(x, y)$ .

Step 5: Obtain the local minima map of  $F_{Tj}(x, y)$ , denoted as  $Q_j(x, y)$ y).

Step 6: Interpolate the minima points in  $Q_i(x, y)$  and generate the lower envelope, denoted as  $L_{Ei}(x, y)$ .

Step 7: Calculate the mean envelope  $M_{Ej}(x, y) = (U_{Ej}(x, y) + L_{Ej}(x, y))$  $(y))/2$ .

Step 8: Calculate the details of the signal in the decomposition process, $F_{Ti+1}(x, y) = F_{Ti}(x, y) - M_{Ei}(x, y)$ .

Step 9: Check whether  $F_{Ti+1}(x, y)$  follows the BIMF properties by finding the standard deviation (SD), denoted as  $D(Eq. (2))$ , between  $F_{Tj+1}(x, y)$  and  $F_{Tj}(x, y)$ , and compare it with the desired threshold.

$$
D = \sum_{x=1}^{M} \sum_{j=1}^{N} \frac{|F_{Tj+1}(x, y) - F_{Tj}(x, y)|^2}{|F_{Tj}(x, y)|^2}
$$
(2)

where  $(x, y)$  is the coordinate, M is the total number of rows and N is the total number of columns of the 2D data. The value of D is usually chosen to be 0.5 to ensure that the mean value of BIMF is close to 0.

Step 10: If  $F_{Ti+1}(x, y)$  meets the criteria according to step 9, then  $F_i(x, y) = F_{Ti+1}(x, y)$ , set  $S_{i+1}(x, y) = S_i(x, y)$  and  $i = i + 1$ , and go to step 11. Otherwise set  $j = j + 1$ , go to step 3 and continue up to step 10.

Step 11: Determine whether  $S_i(x, y)$  has less than three extrema points, and if so, the residual  $R(x, y) = S_i(x, y)$ , and the decomposition is complete. Otherwise, go to step 2 and continue up to step 11.

In the process of extracting BIMFs, the number of extreme points in  $S_{i+1}(x, y)$  should be less than the number of extreme points in  $S_i(x, y)$ y). Let the BIMFs and the residual of a signal together be named as bi-dimensional empirical mode components (BEMCs). All the BEMCs compose the original 2D signal as follow

$$
\sum F(x, y) = \sum_{i=1}^{K+1} F_i(x, y) = I(x, y)
$$
\n(3)

where  $F_i(x, y)$  is the i-th BEMC, and K is the total number of BEMCs except the residual.

<span id="page-2-0"></span>

**Fig. 1.** The framework of the proposed approach.

## **3. The proposed approach**

## 3.1. Overview of the proposed approach

This section proposes an FABEMD approach for filtering of workpiece surfaces using HDM. Compared with the original BEMD approach, three aspects are improved: 1) The proposed approach does not need to calculate the minimum Euclidean distance between adjacent extreme points and does not need to calculate adjacent maxima and minima distance array. 2) The proposed approach uses the adaptive window algorithm to optimally select the window size of the order statistics filters. 3) The envelope surface is drawn by the extremum filters and the average filters, so the computation time is greatly saved.

The framework of the proposed approach is shown in Fig. 1, and the procedure involves the following steps.

Step 1: Read the 3D engineering surface data collected by HDM. Step 2: Use the neighboring window algorithm to find local

maxima and local minima of the original surface, and generate the extrema spectrum.

Step 3: Use the developed adaptive window algorithm to select the optimal window size of the order statistics filters.

Step 4: Apply extremum filters to generate the upper and lower envelopes with the optimal window size.

Step 5: Calculate the mean envelope and use the average filter to smooth filtering.

Step 6: Decompose into roughness, waviness and form.

Step 7: Calculate the 3D surface parameters of the decomposed components, amplitude parameters, shape parameters and spacing parameters for surface texture analysis.

## 3.2. Detecting local extrema

In detection of local extrema, the local maxima and minima points from the given data need to be found. The 2D array of local maxima (minima) points is called a maxima (minima) map. This paper uses the neighboring window algorithm to find local maxima points  $P_{ii}$  and local minima points  $Q_{ii}$ . In this algorithm, a data point is considered as a local maximum (minimum), if its value is strictly higher (lower) than all of its neighbors. Let  $A(x, y)$  be an  $M \times N$  2D matrix represented by

$$
A(x, y) = \begin{bmatrix} a_{11} & a_{12} & \dots & a_{1N} \\ a_{21} & a_{22} & \dots & a_{2N} \\ \vdots & \vdots & \dots & \vdots \\ a_{M1} & a_{M2} & \dots & a_{MN} \end{bmatrix}
$$
 (4)

where  $a_{mn}$  is the element of  $A(x, y)$  located in the m-th row and n-th column.

Let the window size for local extrema determination be  $w_{ex} \times w_{ex}$ . Then, the extrema points are calculated by

$$
a_{mn} \triangleq \text{Local Maximum}, \text{ if } a_{mn} > a_{kl};
$$
  
Local Minimum, if  $a_{mn} < a_{kl};$  (5)

where

$$
(6)
$$

Generally, a given 2D data only needs a  $3 \times 3$  window to get an optimum extrema map. A higher window size may result in a lower number of local extrema points for a given data matrix. In order to find extrema points at the boundary or corner, the neighboring points within the window that are beyond the boundary are neglected. For illustration purposes, consider an  $8 \times 8$  matrix given in [Fig.](#page-3-0)  $2(a)$ . The maxima map given in Fig.  $2(b)$  and minima map given in [Fig.](#page-3-0) 2(c) are obtained through applying a  $3 \times 3$  neighboring window for every point in the matrix.

 $\mathbf{0}$ 

 $\begin{array}{c|c}\n0 & 0 \\
\hline\n0 & 8 \\
\hline\n0 & 0\n\end{array}$ 

 $\overline{0}$ 

<span id="page-3-0"></span>





from  $(a)$ 

obtained from (a)

**Fig. 2.** A sample  $8 \times 8$  data matrix using the neighboring window algorithm.

## 3.3. Adaptive window algorithm to select window width for order-statistics filters

After obtaining the extrema map, the next step is to draw the upper and lower envelope. The core of the traditional BEMD approach is the order statistics filter, in which the maximum value filter (MAX Filter) is used to draw the upper envelope, and the minimum value filter (MIN Filter) is used to draw the lower envelope. Order statistics filters are spatial filters whose responses are determined based on ordering (ranking) the elements contained within the data area encompassed by the filters. The response of the filters at any point is determined by the ranking result. For the envelope estimation approach, the most important part is the order statistics filter, and for the order statistics filter, the crucial part is to select an appropriate window size for the filter.

There are four types of the window sizes ( $d_1 \leq d_2 \leq d_3 \leq d_4$ ) for an order statistic filter determined by the extrema spectrum (Eq.  $(7)$ ).

 $w_{en} = d_1 = \text{minimum} \{ \text{minimum} \{ d_{\text{adj-max}} \}, \text{ minimum} \{ d_{\text{adj-min}} \} \}$  $w_{en} = d_2 = \text{max} \text{imum} \{ \text{minimum} \{ d_{\text{adj-max}} \}, \text{ minimum} \{ d_{\text{adj-min}} \}$  $w_{en} = d_3 = \text{min}\, \text{imum}\{ \text{maximum}\{ d_{\text{adj-max}}\}, \ \text{max}\, \text{imum}\{ d_{\text{adj-min}} \} \}$  $w_{en} = d_4 = \text{max} \text{imum} \{\text{maximum} \{d_{\text{adj-max}}\}, \text{ max} \text{imum} \{d_{\text{adj-min}}\}$ (7)

where  $w_{en}$  is the window size of an order statistic filter,  $d_{\text{adi}-\text{max}}$ is adjacent maxima distance array and d is adjacent minima distance array.

There is always an optimal window size of an order statistic filter in the interval  $[d_1, d_4]$  for a workpiece surface, which makes the FABEMD approach have the best filtering results. It is usually difficult to adaptively choose an optimal window size for a workpiece surface. Therefore, an adaptive window algorithm is developed to automatically select the optimal window size of order statistics filters. The flow chart of the proposed adaptive window algorithm is shown in Fig. 3, and the specific implementation process is described as follows.

Step 1: Read the workpiece surfaces data, obtain roughness using Gaussian filter and calculate the root mean square roughness parameter  $S_{qg}$  as the reference value.

$$
S_{qg} = \sqrt{\frac{1}{A} \iint_{A} z^2(x, y) \, dx \, dy}
$$
 (8)

Step 2: Calculate the window size d of order statistics filters and the original window size  $d$  as shown in Eq.  $(9)$ .

$$
d = \frac{1}{2} \times \sqrt{\frac{M \times N}{n_{extrem}}} \tag{9}
$$



**Fig. 3.** Flow chart of the adaptive window algorithm.

where  $M \times N$  is the image size, and  $n_{extrem}$  is the sum of the numbers of localized maxima and minima. A value of d corresponds to the distance between extrema in case of its uniform distribution.

$$
S_{qf} = \sqrt{\frac{1}{A} \iint_{A} z^2(x, y) \, dx \, dy}
$$
 (10)

<span id="page-4-0"></span>

(a) upper envelope matrix using maximum filter before smoothing



(b) lower envelope matrix using minimum			
	before smoothing		

**Fig. 4.** The upper and lower envelope matrix using maximum filter and minimum filter before smoothing.

Step 3: According to the original window size d, obtain workpiece surface roughness using FABEMD filter and calculate the root mean square roughness parameter  $S_{qf}$ .

Step 4: Calculate the deviation ratio  $\delta$  (Eq. (11)). When  $\delta$  < 0.1, go to step 6, otherwise, go to step 5.

$$
\delta = \frac{|S_{qg} - S_{qf}|}{|S_{qg}|} \times 100\%
$$
\n(11)

Step 5: If  $S_{\text{df}} < S_{\text{qg}}$ , then increase the window size of order statistics filters, set  $d = d + 2$ , and return to step 3 until  $\delta$  < 0.1. If  $S_{qf} > S_{qg}$ , reduce the window size of order statistics filters, set  $d = d - 2$ , and return to step 3 until  $\delta$  < 0.1.

Step 6: If  $\delta$  < 0.1, stop searching, obtain the optimal window size  $d_{opt}$ , and the program ends.

## 3.4. Generating envelopes

After determining the optimal window size of order statistics filter for envelope information, the maximum and minimum filters are applied to obtain the upper and lower envelopes,  $UE_{ij}$  and  $LE_{ij}$ respectively

$$
UE_{ij}(x, y) = \max_{(s, t) \in Z_{xy}} \{S_{ij}(s, t)\}
$$
\n(12)

$$
LE_{ij}(x, y) = \min_{(s,t) \in Z_{xy}} \left\{ S_{ij}(s, t) \right\}
$$
\n(13)

In Eq. (12), the value of the upper envelope  $UE_{ii}$  at any point  $(x, y)$ is the maximum value of the elements in  $S_{ij}$  in the region defined by  $Z_{xy}$ .  $Z_{xy}$  is the square region of size  $W_{en} \times W_{en}(W_{en} = d_{opt})$  centered at any point  $(x, y)$  of  $S_{ii}$ . Similarly, the value of the lower envelope  $LE_{ii}$  at any point (x, y) is the minimum value of the elements in  $S_{ii}$ in the region defined by  $Z_{xy}$  in Eq. (13). It should be noted that the maximum filter and minimum filter produce new 2D matrices for upper and lower envelope surfaces from the given 2D data matrix, and they do not alter the actual 2D data. Since smooth continuous surfaces for upper and lower envelopes are preferable, averaging smoothing operations are carried out on both  $UE_{ii}$  and  $LE_{ii}$  by applying the same window size for corresponding order statistics filters. The averaging smoothing operations are expressed as

$$
UE_{ij}(x, y) = \frac{1}{w_{sm} \times w_{sm}} \sum_{(s, t) \in Z_{xy}} UE_{ij}(s, t)
$$
\n(14)

$$
LE_{ij}(x, y) = \frac{1}{w_{sm} \times w_{sm}} \sum_{(s,t) \in Z_{xy}} LE_{ij}(s, t)
$$
\n(15)

where  $Z_{xy}$  is the square region of size  $W_{sm} \times W_{sm}$  centered at any point  $(x, y)$  of  $UE_{ij}$  or  $LE_{ij}$ ,  $W_{sm}$  is the window width of the averaging smoothing filter and  $W_{\rm sm}$  =  $W_{\rm en}$  =  $d_{\rm opt}$ .

The operation in Eq.  $(14)$  is the arithmetic mean filtering. From the smoothed envelopes  $UE_{ii}$  and  $LE_{ii}$ , the mean or average envelope  $ME_{ii}$  is calculated as

$$
ME_{ij} = (UE_{ij} + LE_{ij})/2
$$
\n(16)

 $A$  3  $\times$  3 window for maximum and minimum filters is applied to the data matrix of [Fig.](#page-3-0)  $2(a)$ , and the results in the upper and lower envelope matrices are shown in Fig.  $4(a)$  and (b), respectively. Window width  $W_{en}$  obtained by Type-3 is 3. The averaging smoothing operations are applied to Fig.  $4(a)$  and (b), and the results in the smoothed upper and lower envelope matrices are shown in [Fig.](#page-5-0)  $5(a)$ and (b), respectively. The mean envelope matrix produced by aver-aging the matrices of [Fig.](#page-5-0)  $5(a)$  and (b) is shown in Fig.  $5(c)$  according to Eq. (16).

In the BEMD approach, SD criterion  $(Eq. (2))$  $(Eq. (2))$  is employed as the most important stopping criterion, and the maximum number of allowable iterations is used as an auxiliary stopping criterion to prevent the occurrence of over-sifting.

The correlation coefficient is used to evaluate the similarity between two vectors.

$$
r = \frac{\sum_{m} \sum_{n} (A_{mn} - \overline{A})(B_{mn} - \overline{B})}{\sqrt{\left(\sum_{m} \sum_{n} (A_{mn} - \overline{A})^{2}\right)\left(\sum_{m} \sum_{n} (B_{mn} - \overline{B})^{2}\right)}}
$$
(17)

where  $r$  is utilized to evaluate the correlation coefficient of the matrixes or vectors with the same size.  $\overline{A(B)}$  is the mean value of  $A$  (B). The number of rows and columns of A and B is M and N, respectively. The larger the correlation coefficient is, the bigger the similarity is. Conversely, the smaller the correlation coefficient is, the smaller the similarity is.

## **4. Simulation experiment**

To verify the performance of the proposed approach, a simulated 3D surface is randomly generated and filtered using the proposed FABEMD approach. Then, the filtering result is compared with the original BEMD approach. The size of the simulated surface is 42 mm  $\times$  42 mm, the sampling interval is 0.1 mm, and the numerical expression of the surface is described as follows.

$$
z(x, y) = 0.8 \times x + 0.8 \times \sin(0.4 \times \pi \times y) + 0.5
$$
  
× 
$$
normal(0, 0.1)0 \le x \le 42 \text{mm}, 0 \le y \le 42 \text{mm}
$$
 (18)

where normrnd ( $\mu$ ,  $\delta$ ) denotes random number following the normal distribution with mean parameter  $\mu$  = 0 and standard deviation parameter  $\delta$ =0.1. 0.5 × normrnd(0, 0.1)(a random noise) is the

<span id="page-5-0"></span>



(a) upper envelope matrix after smoothing

(b) lower envelope matrix after smoothing



(c) mean envelope matrix obtained by averaging the data in (a) and (b)

**Fig. 5.** The envelope matrix after smoothing.



**Fig. 7.** Filtering result of simulated surface using the proposed FABEMD approach.

roughness component,  $0.8 \times \sin(0.4 \times \pi \times y)$  (a sinusoidal function) is the waviness component and  $0.8 \times x$  (an inclined surface) is the form component. The simulated surface and its components are shown in Fig. 6.

Fig. 7 shows the filtering results using the FABEMD approach to the simulated surface. From Fig. 7, it can be seen that Figs.  $6(b)$ – $(d)$ and  $7(b)$ –(d) have obvious similarity. The correlation coefficients of Figs.  $6(b)$ –(d) and  $7(b)$ –(d) are 0.9423, 0.9701 and 0.9997 respectively. Therefore, the proposed FABEMD approach can properly

separate the simulated surface into different surface components and can effectively eliminate mode mixing.

The simulated surface is decomposed by the original BEMD approach and the decomposition results are shown in [Fig.](#page-6-0) 8. From [Fig.](#page-6-0) 8, it can be seen that two sets of BIMF components (BIMF1 and BIMF2, BIMF3 and BIMF4) have a similar scale and mutual influence. According to Eq. [\(17\),](#page-4-0) the correlation coefficients of BIMF1 and BIMF2, BIMF3 and BIMF4 are 0.9349 and 0.7596 respectively. The three simulated components cannot be separated into different BIMFs, and the mode mixing problem occurs.

<span id="page-6-0"></span>

**Fig. 8.** Filtering result of simulated surface using the original BEMD approach.

## **5. Case studies**

In order to further validate the effectiveness of the proposed approach, the point cloud data of three different workpiece surfaces collected by HDM are used for filtering analysis. Gaussian filter (ISO 11562:1996, ASME B46.1-2002), the FABEMD-based filter and the BEMD-based filter are applied respectively, and then the filtering performances of these three filters are analyzed.

The 3D Gaussian filter is a 3D extension of 2D Gaussian filter, which is realized by the convolution of 3D surface data and the 2D weight function. The weighting function of Gaussian filter for surface texture analysis is

$$
S(x, y) = \frac{1}{\alpha^2 \lambda_{xc} \lambda_{yc}} \exp[-\left[\pi(\frac{x}{\alpha \lambda_{xc}})^2 + \pi(\frac{y}{\alpha \lambda_{yc}})^2\right]]
$$
 (19)

where  $\lambda_{xc}$  and  $\lambda_{yc}$  are the cutoff wavelengths in the x and y directions, and  $\alpha = \sqrt{\ln 2/\pi} = 0.4697$ . In the paper, set  $\lambda_{\text{xc}} = \lambda =$ 0.64mm.

In order to evaluate the characteristics of 3D surface topography, some representative 3D surface parameters are selected, including surface amplitude parameters  $S_a$ ,  $S_q$  and  $S_t$ , surface shape parameters  $S_{ku}$ , and surface spacing parameters  $S_{al}$  and  $S_{tr}$ .

## (1) Surface amplitude parameters

Surface amplitude parameter is the description of surface height deviations. The parameters  $S_a$ ,  $S_q$  and  $S_t$  are selected.

The average roughness parameter  $S_a$  reflects the deviation of arithmetic mean distribution of the mean surface data

$$
S_a = \frac{1}{A} \int \int \int_A |z(x, y)| dx dy
$$
\n(20)

where  $Z(x, y)$  is the height value of the point located in line x and column y and A is the evaluation area.

The root mean square roughness  $S_q$  is the standard deviation of the sample to reflect the surface roughness

$$
S_q = \sqrt{\frac{1}{A} \int \int_A z^2(x, y) dx dy}
$$
 (21)

The maximum height of texture surface represents the maximum fluctuation of the sample surface

$$
S_t = |\max(z(x, y))| + |\min(z(x, y))|
$$
 (22)

## (2) Surface shape parameters

Surface shape parameters reflect the height shape characteristics of surface texture. Surface kurtosis  $S_{ku}$  reflects the surface height distribution

$$
S_{ku} = \frac{1}{sq^4} \left[ \frac{1}{A} \int \int_A z^2(x, y) dx dy \right]
$$
 (23)

## (3) Surface spacing parameters

Surface spacing parameters reflect the spatial distribution of a sample surface. The fastest autocorrelation decay length  $S_{al}$  represents the composition of surface components, and  $S_{al} \in (0, 1)$ . The smaller the value of  $S_{al}$  is, the bigger the probability of the surface with low frequency components is. The larger the value of  $S_{al}$ is, the bigger the probability of the surface with high frequency components is.  $S_{ol}$  is the horizontal distance of the autocorrelation function (ACF) that has the fastest decay in any direction to a specified threshold value  $\eta$ , and  $0 < \eta < 1$  ( $\eta = 0.1$  in this study).

$$
S_{al} = \frac{Min}{\tau_x, \tau_y \in R} (\sqrt{\tau_x^2 + \tau_y^2}) \text{ where } R = \{ (\tau_x, \tau_y) : ACF(\tau_x, \tau_y) \le \eta \qquad (24)
$$

The ACF of a 3D surface is defined as a convolution of the surface with itself

$$
ACF(\tau_x, \tau_y) = \frac{\int \int_A z(x, y)z(x - \tau_x, y - \tau_y)dxdy}{\int \int_A z(x, y)z(x, y)dxdy}
$$
(25)

where  $\tau_x$ ,  $\tau_y$  are the x-direction and y-direction shifts respectively.

The surface texture aspect ratio parameter  $S_{tr}$  (Eq. (26)) reflects the surface texture characteristics of sample surface. The smaller the value of  $S_{tr}$  is, the more obvious the surface texture is. The larger the value of  $S_{tr}$  is, the less obvious the surface texture is.

$$
S_{tr} = \frac{\lim_{\tau_x, \tau_y \in R} (\sqrt{\tau_x^2 + \tau_y^2})}{\lim_{\tau_x, \tau_y \in R} (\sqrt{\tau_x^2 + \tau_y^2})} \text{ where } R = \{(\tau_x, \tau_y) : ACF(\tau_{x, \tau_y}) \le \eta \qquad (26)
$$

## 5.1. Case study I

The first workpiece surface is the surface of a pump valve plate, and its height map is shown in [Fig.](#page-7-0) 9. A surface sample is arbitrarily selected from the surface, the size of the surface sample is 6.4 mm  $\times$  6.4 mm (shown in Fig. [10\(a](#page-7-0))) and the sampling interval is 0.01 mm. The results of the FABEMD-based filter are shown in [Fig.](#page-7-0) 10. Fig. [10\(b](#page-7-0))–(d) represent roughness, waviness and form respectively.

Because of the boundary effects caused by the local weighted average in the Gaussian filter, the evaluation area of the Gaussian filter needs to be subtracted the first and last wavelengths from the sum in order to obtain good filtering results, and then the actual area becomes 5.12 mm  $\times$  5.12 mm. The surface sample is separated into two components: one component is the mean surface including the waviness surface and the form surface, and the other one is the roughness surface.

[Fig.](#page-7-0) 11 presents a comparison of mean surfaces obtained by Gaussian filter and FABEMD-based filter without discarding any boundary region, and the actual size of evaluation area is 6.4 mm  $\times$  6.4 mm. [Fig.](#page-7-0) 11(a) illustrates that the values on the boundary of the mean surface by Gaussian filter are close to zero

<span id="page-7-0"></span>

**Fig. 9.** The height map of the valve plate surface.

and there are obvious distortions on the boundary. This is the result of the convolution operation. As shown in Fig.  $11(b)$ , there is no distortion in the FABEMD filtering results. Therefore, due to the boundary effect of Gaussian filter, it is necessary to remove the boundary in practical application. It is feasible for the original data to be long enough. However, when the original data length is limited, and then the boundary area is given up, there will be inevitably some influences on the evaluation results. The FABEMD approach does not need to predict the extrema points on the boundary, so the boundary distortions are avoided. The FABEMD-based filter is more applicable than Gaussian filter.

[Fig.](#page-8-0) 12 shows six samples of the oil pump valve, and the size of each sample surface is  $6.4$  mm  $\times$   $6.4$  mm. Then Gaussian filter, the FABEMD-based filter and the BEMD-based filter are applied to the six samples, and the filtering results are compared. To be convenient for the comparison, the actual evaluation area of three filters is set as  $5.12$  mm  $\times$   $5.12$  mm and the sampling interval is 0.01 mm.

[Table](#page-8-0) 1 shows the surface amplitude parameters obtained by Gaussian filter and FABEMD-based filter. It can be found from the last three columns in [Table](#page-8-0) 1 that the mean differences are close to 5% in  $S_a$  values, close to 4% in  $S_a$  values and close to 10% in  $S_t$  values.

[Table](#page-8-0) 2 shows the surface amplitude parameters obtained by Gaussian filter and the BEMD-based filter. It can be found from the last three columns in [Table](#page-8-0) 2 that the mean differences are close to 200% in  $S_a$  values, close to 190% in  $S_a$  values and close to 130% in  $S_t$  values. It can be seen that the mean differences of the surface amplitude parameters obtained by Gaussian filter and the FABEMDbased filter are less than 10%. Nevertheless, the mean differences of



**Fig. 10.** Filtering results of a surface sample using the FABEMD filter.



**Fig. 11.** Comparison of mean surfaces obtained by Gaussian filter and FABEMD.

<span id="page-8-0"></span>The comparison of surface amplitude parameters using the FABEMD-based filter and Gaussian filter.



Difference is calculated by:  $\frac{\text{NFABEMDvalue}-\text{Gaussian value}}{\text{Gaussian value}}$  | × 100%.

## **Table 2**

The comparison of surface amplitude parameters using original BEMD-based filter and Gaussian filter.



#### **Table 3**

The comparison of surface shape and surface space parameters using the FABEMD-based filter and Gaussian filter.





**Fig. 12.** The distribution map of six sample surface.

the surface amplitude parameters obtained by Gaussian filter and the original BEMD-based filter are about 130%-200%. Therefore, the FABEMD-based filter can reflect the sample surface amplitude, but the BEMD-based filter cannot reflect the sample surface amplitude.

Table 3 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in Table 3 that the mean differences are close to 11% in  $S_{ku}$  values, close to 12% in  $S_{al}$  values and close to 11% in  $S_{tr}$ values. In general, the mean differences of shape parameters and spacing parameters are within 20%.

[Table](#page-9-0) 4 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in [Table](#page-9-0) 4 that the mean differences are close to 18% in  $S_{ku}$  values, close to 100% in  $S_{al}$  values and close to 15% in  $S_{tr}$  values.

[Table](#page-9-0) 5 lists the comparison results of the window width and computational time using the BEMD-based filter and FABEMDbased filter. It can be found that the optimal window width of the order statistics filters searched by the FABEMD-based filter is 15 or 17. That is to say, the window width of the order statistics filter is relatively stable in the filtering process, which means that the surface topography of the workpieces is more uniform. However, the window width of the order statistics filters searched by the BEMDbased ranges from 57 to 69 and the filter window width changes greatly, which cannot reflect the surface topography. Moreover, the filtering time of the FABEMD-based filter is less than 30% of the filtering time of the BEMD-based filter, so the computational efficiency is improved.

## 5.2. Case study II

The second surface is the joint surface of an engine cylinder head, which is made of aluminum. The height map of this surface is shown in [Fig.](#page-9-0) 13. Eight locations are selected (shown in [Fig.](#page-9-0) 14)

<span id="page-9-0"></span>



The comparison of window width and computational time using the BEMD-based filter and FABEMD-based filter.



Time scale is calculated by:  $\frac{\text{NFABEMD Time}-\text{BEMDTime}}{\text{BEMDTime}}$  |  $\times$  100%.



**Fig. 13.** The height map of the engine cylinder head.



**Fig. 14.** The distribution map of eight sample surfaces.

from this surface with the same size and then eight small surfaces are obtained. Then Gaussian filter, the FABEMD-based filter and BEMD-based filter are applied to the eight sample surfaces and the surface texture parameters are obtained by the three filters.

[Table](#page-10-0) 6 shows the surface amplitude parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in [Table](#page-10-0) 6 that the mean differences are close to 4% in  $S_a$  values, close to 5% in  $S_q$  values and close to 13% in  $S_t$ values. [Table](#page-10-0) 7 shows the surface amplitude parameters obtained by Gaussian filter and the BEMD-based filter. It can be found from the last three columns in [Table](#page-10-0) 7 that the mean differences are close to 320% in  $S_a$  values, close to 320% in  $S_a$  values and close to 250% in  $S_t$ values.

[Table](#page-10-0) 8 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in [Table](#page-10-0) 8 that the mean differences are close to 17% in  $S_{ku}$  values, close to 15% in  $S_{al}$  values and close to 18% in  $S_{tr}$  values. In general, the mean differences of shape parameters and spacing parameters are within 20% [\[7,8\].](#page-15-0)

<span id="page-10-0"></span>The comparison of surface amplitude parameters using the FABEMD-based filter and Gaussian filter.



#### **Table 7**

The comparison of surface amplitude parameters using the BEMD-based filter and Gaussian filter.



#### **Table 8**

The comparison of surface space parameters using FABEMD filter and Gaussian filter.



#### **Table 9**

The comparison of surface space parameters using the BEMD-based filter and Gaussian filter.



Table 9 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in Table 9 that the mean differences are close to 17% in  $S_{ku}$  values, close to 175% in  $S_{al}$  values and close to 32% in  $S_{tr}$  values.

[Table](#page-11-0) 10 shows the comparison results of the window width and computational time using the BEMD-based filter and FABEMDbased filter. It can be seen that the optimal window width of the order statistics filters searched by the FABEMD-based filter is 15 or

17. That is to say, the window width of the order statistics filter is relatively stable in the filtering process, which means that the surface topography of the workpieces is more uniform. The window width of the order statistics filters searched by the BEMD-based filter ranges from 63 to 99 and the filter window width changes greatly, which cannot reflect the surface topography of the workpieces. Moreover, the filtering time of the FABEMD-based filter is less than 15% of the BEMD-based filter's filtering time, so the computational efficiency is improved.

<span id="page-11-0"></span>







**Fig. 15.** The distribution map of eight sample surface.



**Fig. 16.** The height map of the top surface of an engine cylinder block.

## 5.3. Case study III

The third surface is the top surface of an engine cylinder block, which is made of cast iron FC250. Eight locations (shown in Fig. 15) from three top surfaces of engine blocks A, B, and C using HDM (shown in Fig. 16) are selected. Then Gaussian filter, the FABEMDbased filter and BEMD-based filter are applied to the eight sample surfaces and the surface texture parameters are obtained by the three filters.

[Table](#page-12-0) 11 shows the surface amplitude parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in [Table](#page-12-0) 11 that the mean differences are close to 6% in  $S_a$  values, close to 6% in  $S_q$  values and close to 15% in  $S_t$ values. [Table](#page-12-0) 12 shows the surface amplitude parameters obtained by Gaussian filter and the BEMD-based filter. It can be found from the last three columns in [Table](#page-12-0) 12 that the mean differences are close to 80% in  $S_a$  values, close to 70% in  $S_q$  values and close to 20% in  $S_t$  values.

<span id="page-12-0"></span>



The comparison of surface amplitude parameters using the BEMD-based filter and Gaussian filter.



[Table](#page-13-0) 13 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD filter. It can be found from the last three columns in [Table](#page-13-0) 13 that the mean differences are close to 15% in  $S_{ku}$  values, close to 10% in  $S_{al}$  values and close to 10% in  $S_{tr}$  values. [Table](#page-13-0) 14 shows the surface shape and spacing parameters obtained by Gaussian filter and the FABEMD-based filter. It can be found from the last three columns in [Table](#page-13-0) 14 that the mean differences are close to 40% in  $S_{ku}$  values, close to 60% in  $S_{al}$ values and close to 20% in  $S_{tr}$  values.

[Table](#page-14-0) 15 shows the comparison results of the window width and computational time using the BEMD-based filter and FABEMDbased filter. It can be seen that the optimal window width of the order statistics filters searched by the FABEMD filter is 17 or 19. That is to say, the window width of the order statistics filter is relatively stable in the filtering process, which means that the surface topography of the workpieces is more uniform. However, the window width of the order statistics filters searched by the BEMD-based filter ranges from 41 to 53 and the filter window width changes

<span id="page-13-0"></span>



#### **Table 14**

The comparison of surface shape and surface space parameters using BEMD filter and Gaussian filter.



greatly, which cannot reflect the surface topography of the parts. Moreover, the filtering time of FABEMD filter is less than 50% of the BEMD filter's filtering time, so the computational efficiency is improved.

It can be seen from the above three cases that the differences of the surface texture parameters between Gaussian filter and the BEMD-based filter are relatively large. So the BEMD-based filter cannot be directly applied to workpiece surface separations. Nevertheless, for Gaussian filter and the FABEMD-based filter, their

differences of the average roughness parameter  $S_a$  and the root mean square roughness parameter  $S_q$  are close to 6%, and the maximum height of texture surface  $S_t$  is less than 20%. Moreover, the surface shape parameters  $S_{ku}$  and the surface spacing parameters  $S_{al}$  and  $S_t$  are also less than 20%. Because the difference of 10–20% is very common as reported in [[7,8\],](#page-15-0) so the results of three real-world surface data show that the performance of the FABEMD-based filter is similar to the performance of the standard Gaussian filer, but

<span id="page-14-0"></span>



The comparison of surface amplitude parameters using shearlet-based filter and Gaussian filter.



## **Table 17**

The comparison of surface shape and surface space parameters using shearlet-based filter and Gaussian filter.



superior to the BEMD-based filter, moreover, the FABEMD-based filter does not have the boundary distortions.

## 5.4. Comparison with the shearlet-based filter

Take the surface of case study I as an example. The recent developed shearlet-based filter [\[13\]](#page-15-0) has good filtering performances and is applied to further comparison analysis. The cutoff wavelength of shearlet is 0.64 mm. Table 16 shows the surface amplitude parameters obtained by Gaussian filter and the shearlet-based filter. It can be found from the last three columns in Table 16 that the mean differences are close to 11% in  $S_a$  values, close to 9% in  $S_a$  values and close to 11% in  $S_t$  values. Table 17 shows the surface shape and

spacing parameters obtained by Gaussian filter and shearlet-based filter. It can be found from the last three columns in Table 17 that the mean differences are close to 21% in  $S_{ku}$  values, close to 18% in  $S_{al}$ values and close to 23% in  $S_{tr}$ values. The results in [Tables](#page-8-0) 1 and 16 indicate that the FABEMD-based filter and shearlet-based filter have no distinct difference from each other in the surface amplitude parameters. The results in [Tables](#page-8-0) 3 and 17 indicate that the FABEMD filter is better than the shearlet-based filter in the surface shape and spacing parameters. [Table](#page-15-0) 18 shows the differences of the surface amplitude parameters  $S_a$  between Gaussian filter and the Shearlet filter, BEMD-based filter and FABEMD-based filter. It can be found that the differences between Gaussian filter and FABEMD-based filter are close to 4.9% in  $S_a$  values, which is the smallest. It can also be <span id="page-15-0"></span>The comparison of surface amplitude parameters and time using Gaussian filter, shearlet-based filter, BEMD-based filter and FABEMD-based filter.



found that the time of FABEMD-based filter is shorter than Shearlet filter and BEMD-based filter, but slightly longer than Gaussian filter

## **6. Conclusions**

In this paper, a novel filter based on FABEMD approach for workpiece surfaces using HDM is proposed. The neighboring window algorithm is presented to extract local extrema and draw the extrema spectrum. The adaptive window algorithm is developed to realize the automatic acquisition of the window size of the order statistics filters. The average smoothing filter is presented for smooth filtering and generating of the mean envelope. The performance of FABEMD-based filter is validated by the simulated surface data and real-world 3D surface data using HDM. Some conclusions can be drawn.

- (1) The FABEMD-based filter can effectively decompose the simulated surface into three components: roughness, waviness and form, and has good applicability for workpiece surface filtering.
- (2) Compared with the BEMD-based filter, the optimal window width of the order statistic filters searched by the adaptive window algorithm shows its stability and effectiveness, which indicates that the FABEMD-based filter has higher accuracy. The envelope surface in the FABEMD-based filter is drawn by the extremum filters and the average filters, so it has higher efficiency than the BEMD-based filter has. Moreover, the proposed approach does not need to calculate the minimum Euclidean distance between adjacent extreme points and calculate adjacent maxima distance array and adjacent minima distance array.
- (3) Compared with Gaussian filter that has obvious distortion at the surface boundary, the FABEMD-based filter has no boundary distortions, and the filtering results are basically same as those of Gaussian filter.
- (4) Compared with the shearlet-based filter, the results of the FABEMD-based filter on the surface amplitude parameters are similar, and the results on the surface shape and spacing parameters are better than the shearlet-based filter.

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